

Growth of Columnar Co₃Pt Structure with Ru Buffer Layer at Room Temperature

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Abstract

Magnetic Co₃Pt films were sputtered on a Ru(0002)/Pt(111) bilayer on glass substrate at room temperature. The effects of a Ru buffer layer thickness (*t* nm) on magnetic properties and microstructures were studied. AFM surface roughness results revealed that the root mean square roughness (*R_{rms}*) of the Ru/Pt bilayer surface is smaller than 1.5 nm. Granular Ru topography was observed as *t* is larger than 7 nm, which played an important role in influencing the magnetic properties and microstructures of Co₃Pt thin film. In this study, Ru(0002) grew along the Pt(111) underlayer and then became a template for epitaxially growing Co₃Pt(0002) film, in order to enhance the perpendicular magnetic anisotropy (PMA). Maximum *H_c* were obtained as *t*=15, due to the columnar structure formed in the whole Co₃Pt/Ru/Pt film. It demonstrates that a Ru buffer layer is helpful to enhance the PMA of Co₃Pt magnetic thin film and increase out-of-plane squareness (*S₁*) and *H_c*.

Keywords: Perpendicular magnetic anisotropy; Co₃Pt thin film; Buffer layer thickness; Epitaxial growth

Introduction

In order to achieve a higher areal density of magnetic recording media, new developments are constantly coming out one after another. Recently, magnetic tunneling junction (MTJ) based spin transfer torque magneto resistive random access memory (STT-MRAM) has been regarded as the next generation temporary data storage device [1-3]. In this case, material with large magnetocrystalline anisotropy (*K_u*), high coercivity (*H_c*) and good chemical stability is necessary for the fix layer in an MTJ cell. Furthermore, material for a fix layer with a high perpendicular magnetic anisotropy (PMA) can make cells become perpendicular MTJ (p-MTJ), which can further increase recording density [3]. Thus, high PMA *L*₁₀-type FePt and CoPt magnetic alloy thin film has attracted a great deal of research in recent years [4-10]. However, an *L*₁₀ phase transformation temperature is too high, becoming a drawback for further application. Recently, Co₃Pt with an HCP structure has been regarded as a promising candidate to replace *L*₁₀-type FePt and CoPt due to its lower formation temperature (RT~350°C) and similar magnetic properties such as large *K_u* (~2 × 10⁷ erg/cm³) and PMA (*S₁*~0.9), compared with *L*₁₀-type FePt and CoPt [11-16]. Additionally, lower Pt content can make this structure more economical. In order to develop an HCP structural Co₃Pt with high PMA, costly single crystal substrates such as MgO(111) and Al₂O₃(0001) were adopted [17-20], suggesting an obvious limitation in future applications. Thus, it is necessary to fabricate HCP structural Co₃Pt on glass substrate and still retain its attractive magnetic properties. But HCP structural Co₃Pt difficultly grows on glass substrate due to the amorphous substrate plane.

Usually, textured underlayer was adopted to enhance the PMA of magnetic layer on glass substrate [15,16,21], because small lattice mismatch (δ) between magnetic layer and underlayer helps PMA phase epitaxially grows on the lattice sites of underlayer and consequently induced higher PMA of magnetic layer. The δ is used to illustrate the extent of lattice differences of two different materials during epitaxial growth. The δ between two different materials, α and β , can be calculated by the following formula [22]:

$$\delta = \frac{a_\alpha - a_\beta}{a_\alpha} \quad (1)$$

where *a_α* and *a_β* are the lattice parameters of materials α and β , respectively.

Pt(111) shows a flat surface and similar lattice parameters to a Co₃Pt(0002) plane. Thus, the lattice mismatch ($\delta=7.9\%$) at Pt(111)/Co₃Pt(0002) interface provides a template for epitaxially growing Co₃Pt with (0002) orientation [23]. However, if the δ could be further reduced, Co₃Pt films with more (0002) orientation would be expected. To achieve that, HCP Ru(0002) is a proper choice. Figure 1 depicts δ between Co₃Pt(0002), Ru(0002), and Pt(111). Lattice parameters of Co₃Pt(0002) [11 $\bar{2}$ 0], Ru(0002) [11 $\bar{2}$ 0], and Pt(111) [110] are 0.255, 0.270 and 0.277 nm, respectively. Therefore, δ between Ru(0002) [11 $\bar{2}$ 0] and Co₃Pt(0002) [11 $\bar{2}$ 0] is 5.9%, which is smaller than the lattice misfit between Co₃Pt(0002) [11 $\bar{2}$ 0] and Pt(111) [110]. However, it is difficult to deposit pure HCP Ru(0002) structural film directly on glass substrate in our experience; usually, the second phase appears easily. But using a Pt(111) to induce the Ru(0002) is workable since the δ between Pt(111) and Ru(0002) is 2.6%, which is helpful for Ru(0002) growth. Therefore, an HCP Co₃Pt(0002) structure is expected to be fabricated by adopting a Pt/Ru bilayer film. In this study, Ru layers with

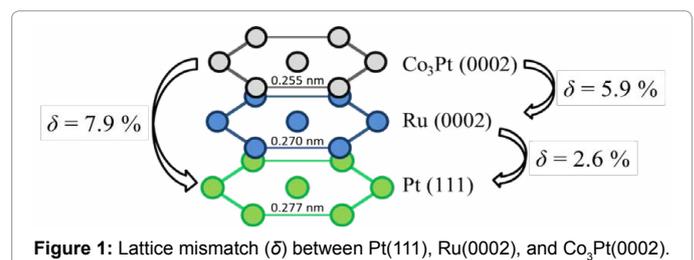


Figure 1: Lattice mismatch (δ) between Pt(111), Ru(0002), and Co₃Pt(0002).

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different thicknesses (t nm) were prepared as the buffer layer between a Pt underlayer and a Co₃Pt magnetic layer, and the effect of Ru buffer layer thickness on magnetic properties and microstructures of Co₃Pt films was investigated.

Experimental Section

In this study, HCP structural Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm)/glass substrate was fabricated by a sputtering method in a high vacuum magnetron sputtering system. The base pressure of the chamber was greater than 2×10^{-7} Torr. Argon was selected to be the working gas and the pressure was set to 10 mTorr. Direct current (DC) power was adopted to supply the sputtering system. Before sputtering the magnetic Co₃Pt layer, Ru layer with varied t was sputtered on a 20 nm-thick textured Pt(111) underlayer on glass substrate at 350°C, where t was 0, 7, 15 and 25 nm, respectively. After that, the substrate was cooled to room temperature (RT) for depositing Co₃Pt film at a 10 nm thickness. Two-inch Co, Pt, and Ru targets with purity levels higher than 99.99 at.% was adopted as the sputtering sources. The Pt content in the Co-Pt alloy thin film was controlled by adjusting the number of Pt chips on the Co target. The chemical composition of Co-Pt film was 76 at.% Co and 24 at.% Pt, which was confirmed by energy dispersion spectroscopy (EDS) equipped on a field-emission scanning electron microscope (FE-SEM). The thickness and surface roughness of the films were checked by an atomic force microscope (AFM). The surface morphology was observed by SEM. Magnetic properties were measured by a vibrating sample magnetometer (VSM). The crystallization was characterized by X-Ray diffractometer (XRD) with Cu-K α radiation. The microstructure was investigated using a high-resolution transmission electron microscope (HR-TEM) with 200 keV accelerating voltages.

Results and Discussion

In order to understand the effect of the Ru thickness on surface roughness in Ru/Pt bilayers, the topography of Ru(t nm)/Pt(20 nm) bilayers were identified by AFM and shown in Figure 2a-2d. Figure 2e is the relationship between t and the root mean square roughness (R_{rms}) of Ru/Pt bilayers. All the bilayer films have flat surface, where the R_{rms} of surfaces are less than 1.5 nm. In Figure 2a, numerous small dots are observed at $t=0$, which shows the lowest R_{rms} (0.23 nm) in Ru/Pt bilayers. Further increasing t would increase the R_{rms} . When $t=7$, small particles could be observed on the surface (marked by white arrow in Figure 2b), so called granular topography. The amount of particles increase as t is increased to 15 nm (Figure 2c). The particles size was also raised and the maximum R_{rms} ($R_{rms}=1.36$) was obtained. When t keeps increasing to 25 nm (Figure 2d), the amount and size of particles decreased slightly, leading the R_{rms} decreasing to 0.53 nm. Apparently, the particles played an important role in affecting the R_{rms} in Ru/Pt bilayer. Next, Co₃Pt magnetic layer was sputtered on the Ru/Pt bilayer, therefore it is expected that granular topography influence Co₃Pt film growth.

Figure 3a-3d show hysteresis loops of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm) films, where $t=(a)$ 0, (b) 7, (c) 15 and (d) 25 nm. Figure 3f exhibits the functions of out-of-plane squareness (S_{\perp}) and coercivity ($H_{c\perp}$) on the thickness of Ru layer. Without a Ru buffer layer ($t=0$), the film shows lower $H_{c\perp}$ (~ 0.23 kOe) and S_{\perp} (~ 0.23). Then, the $H_{c\perp}$ and S_{\perp} increase as t increases. The maximum $H_{c\perp}$ (~ 1.7 kOe) and S_{\perp} (~ 0.43) appear at $t=15$, indicating that a higher amount of perpendicular hard magnetic structure exists in the Co₃Pt film. Further increasing t decreased $H_{c\perp}$ and S_{\perp} . Combining with R_{rms} in Ru/Pt bilayer, as shown in Figure 2, can obtain that the highest $H_{c\perp}$ with the highest R_{rms} (1.36

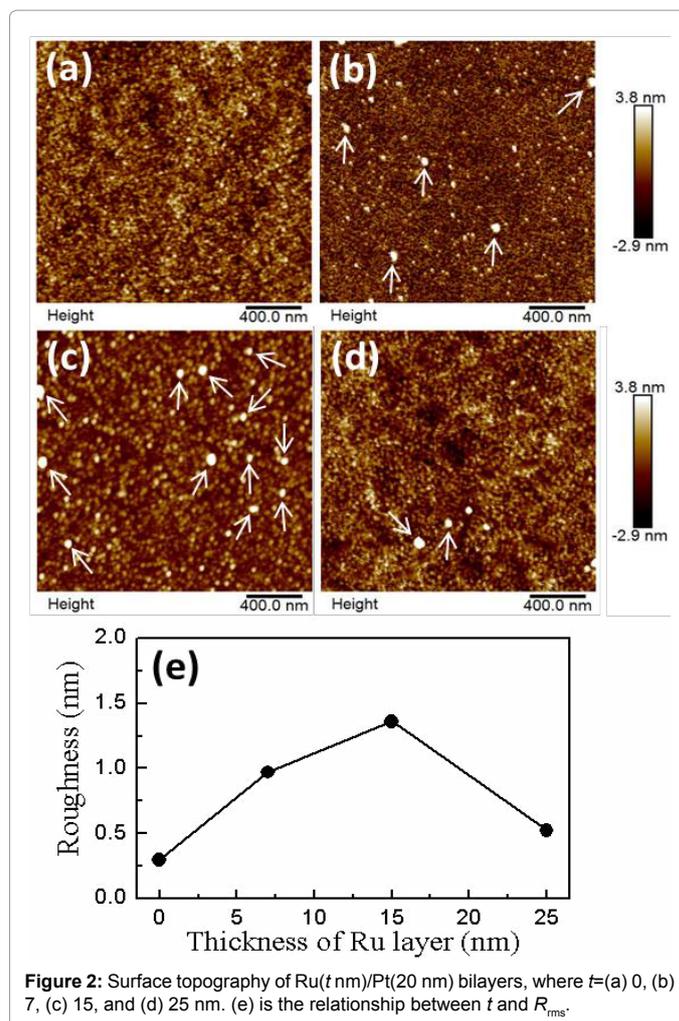


Figure 2: Surface topography of Ru(t nm)/Pt(20 nm) bilayers, where $t=(a)$ 0, (b) 7, (c) 15, and (d) 25 nm. (e) is the relationship between t and R_{rms} .

nm) is at $t=15$. Increasing t to 25 nm leads R_{rms} to decline and further reduce $H_{c\perp}$ and S_{\perp} .

Figure 4a shows XRD patterns of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm), where $t=0, 7, 15$ and 25 nm, respectively. It is clear to see the strong Pt(111) diffraction peaks in all samples, indicating formation of a textured Pt(111) underlayer. However, Co₃Pt(0002) diffraction peaks are weak at $t=0$, revealing poor crystallization. Increasing the t to 7 nm quickly enhances the intensity of the Ru(0002) peak. Although little Al CoPt(111) forms at $2\theta=41.9^\circ$, a clear Co₃Pt(0002) diffraction peak appears at $2\theta=43.2^\circ$, indicating the Ru(0002) has the benefit to grow a Co₃Pt(0002) phase. However, more Co₃Pt(0002) does not increase the $H_{c\perp}$. Further increasing the t to 25 nm presents highest Ru(0002) peak, but lower Co₃Pt(0002) peak. Figure 4b presents the lattice constants of FCC Pt(111), HCP Ru(0002), and HCP Co₃Pt(0002), calculating from Figure 4a. The dash lines are the lattice constants from bulk material [24-26]. All the Pt(111) show a similar lattice constant, indicating that the underlayer provides a stable template for Ru film growth. When $t > 7$, the lattice spacing of Ru(0002) increases with t . As lattice constant of Pt is larger than Ru, this phenomena suggests that the Ru(0002) lattice is adjusted by the Pt(111) plane. Increasing the thickness of Ru layer continuously expands its lattice constant. The upper Co₃Pt(0002) layer is also fitted with a lattice spacing with Ru(0002) when $t > 7$, evidencing the epitaxial growth between Ru(0002) and Co₃Pt(0002) planes [21,27].

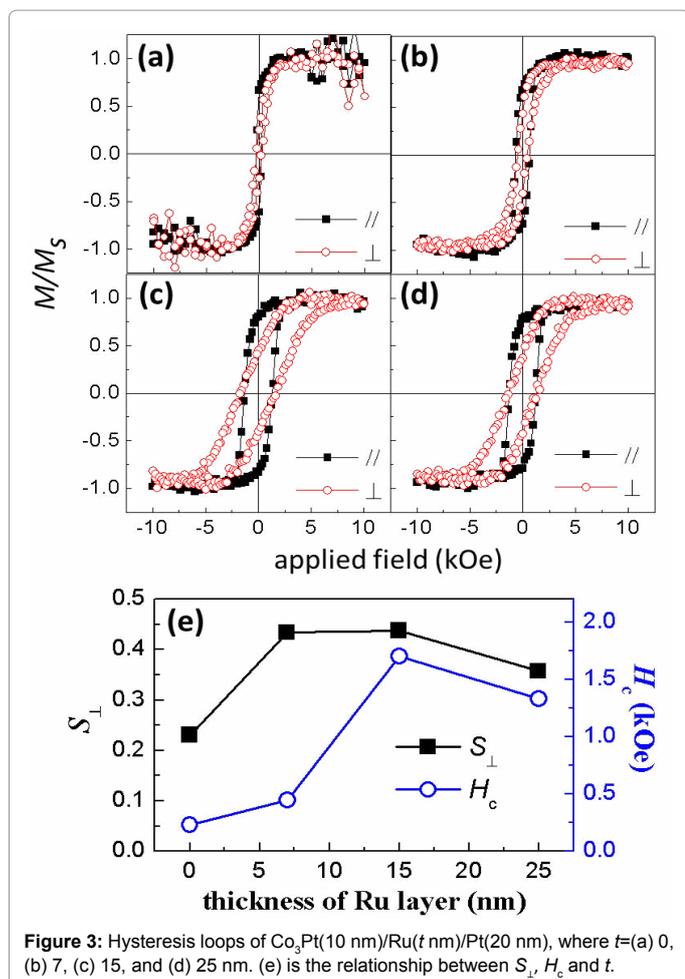


Figure 3: Hysteresis loops of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm), where $t=(a)$ 0, (b) 7, (c) 15, and (d) 25 nm. (e) is the relationship between S_{\perp} , H_c and t .

A comparison of Figures 2e, 3e and 4b finds that the surface roughness between Ru(0002) and Co₃Pt(0002) is the major effect on crystal quality of Co₃Pt(0002) structure. Thus, losing granular topography at $t=25$ decreases the amount of Co₃Pt(0002) orientation, thereby achieving a low S_{\perp} .

In order to understand the granular topography effect, the internal microstructures of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm) films are shown in Figure 5. Figure 5a-5c show cross-sectional TEM bright field images of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm) trilayer films with $t=0, 7$ and 15 nm, and the corresponding magnified images are shown in Figures 5d-5f, respectively. In Figure 5a, a flat interface between Pt and Co₃Pt can be clearly observed at $t=0$, which is in agreement with the AFM results (Figure 2a). In the enlarged image (Figure 5d), Pt(111) lattice images appeared. However, a Co₃Pt lattice image seems unclear observation, evidencing that the flat Pt(111) underlayer is insufficient to grow HCP Co₃Pt(0002) at RT. This result is also predicted by the XRD, which show a strong Pt(111) but a weak Co₃Pt(0002) diffraction peak. When t increases to 7 nm, as shown in Figure 5b, the film shows continuous film structure with less grain boundary, which has a less pinning site for the magnetic reversal process and further reduces H_c [28,29]. Figure 5e shows the corresponding magnified image. Very clear lattice images are observed and the lattice distances are identified as 0.224 nm, 0.215 nm and 0.208 nm, which correlate with Pt(111), Ru(0002), and Co₃Pt(0002), respectively. This is the proof that a Ru(0002) buffer layer grows along the Pt(111) underlayer and further induces the formation

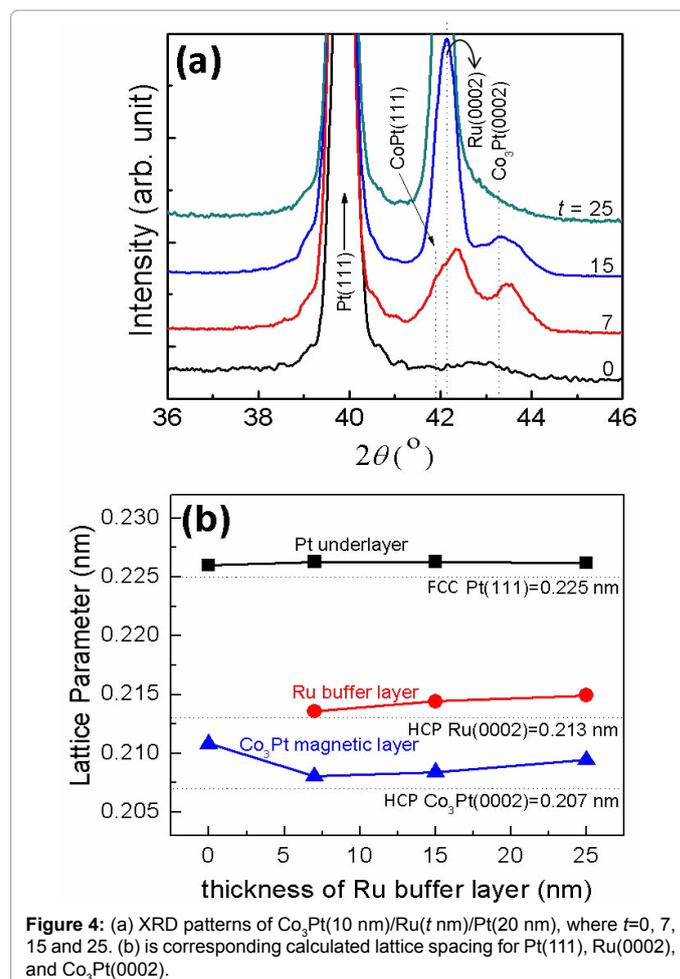


Figure 4: (a) XRD patterns of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm), where $t=0, 7, 15$ and 25 . (b) is corresponding calculated lattice spacing for Pt(111), Ru(0002), and Co₃Pt(0002).

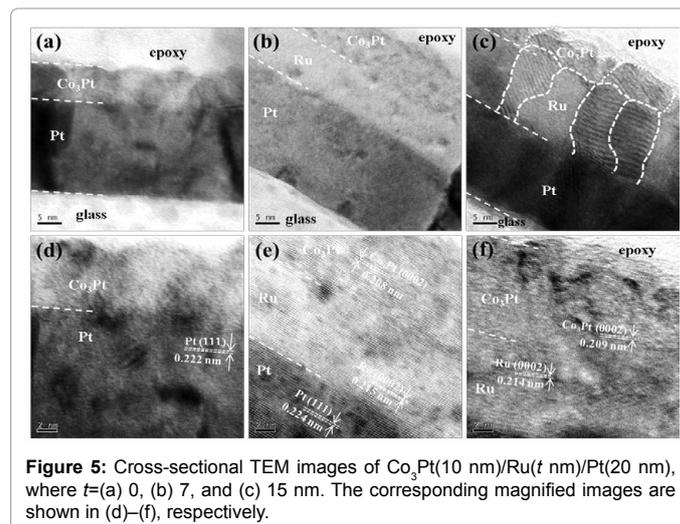


Figure 5: Cross-sectional TEM images of Co₃Pt(10 nm)/Ru(t nm)/Pt(20 nm), where $t=(a)$ 0, (b) 7, and (c) 15 nm. The corresponding magnified images are shown in (d)–(f), respectively.

of Co₃Pt(0002). With a further increase of t to 15 nm, as shown in Figure 5c, it is clear that the Ru buffer layer transfers into a columnar structure (marked as white dash line), which resulting granular topography in the AFM results (Figure 2d). This columnar growth behavior may result in a higher R_{rms} . Granular structural buffer layers provide a template which helps Co₃Pt to grow along it and allows Co₃Pt to become a columnar structure which makes the film discontinuous

and obtains higher H_{cl} . In Figure 5f, the clear Ru lattice is helpful for Co₃Pt(0002) growth at RT.

Conclusion

In this study, the correlation between magnetic properties and microstructures of Co₃Pt films sputtered on various thicknesses of Ru buffer layer at RT were investigated. Results point out that the Ru/Pt bilayer shows a granular topography. When $t=7$, the Co₃Pt film shows a high S_{\perp} but a lower H_{cl} due to less pinning site in the continuous magnetic film structure. The maximum R_{rms} can be observed at $t=15$, which also shows the greatest H_{cl} . The microstructure indicates that a Ru(0002)/Pt(111) bilayer structure could enhance the Co₃Pt(0002) phase and S_{\perp} . The films form a columnar structure and further increase H_{cl} to 1.7 kOe when $t=15$. Kept increasing t to 25 nm decreases H_{cl} and S_{\perp} . Our results indicate that a Ru buffer layer is helpful for Co₃Pt(0002) growth of RT-deposited Co₃Pt magnetic thin films, which can be the basis for future development of Co₃Pt magnetic films at RT.

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